

[54] **WAFER PROBE PLATE HOLDER**

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[**] Term: **14 Years**

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[52] U.S. Cl. **D10/103**

[58] Field of Search **D10/46, 80, 103; D8/349, 399; 324/158 F, 158 P**

[56] **References Cited**

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[57] **CLAIM**

The ornamental design for a wafer probe plate holder, as shown and described.

DESCRIPTION

FIG. 1 is a front elevational view of a wafer probe plate holder showing my new design, the rear, right and left side elevational views being identical; FIG. 2 is a top plan view; FIG. 3 is a bottom plan view; and FIG. 4 is a cross sectional view thereof taken along line 4-4' of FIG. 2 thereof.

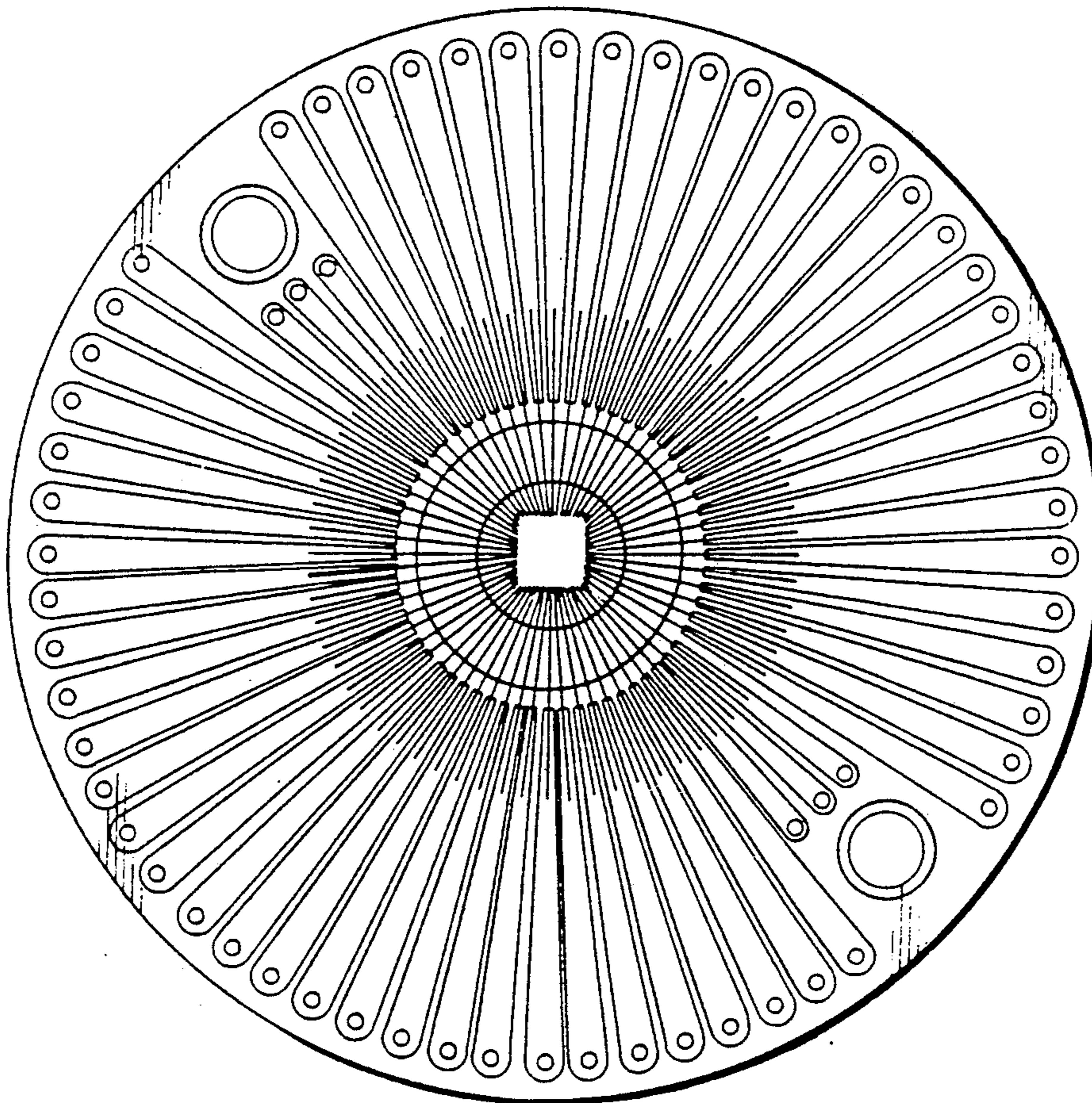


FIG. 1



FIG. 4



FIG. 2

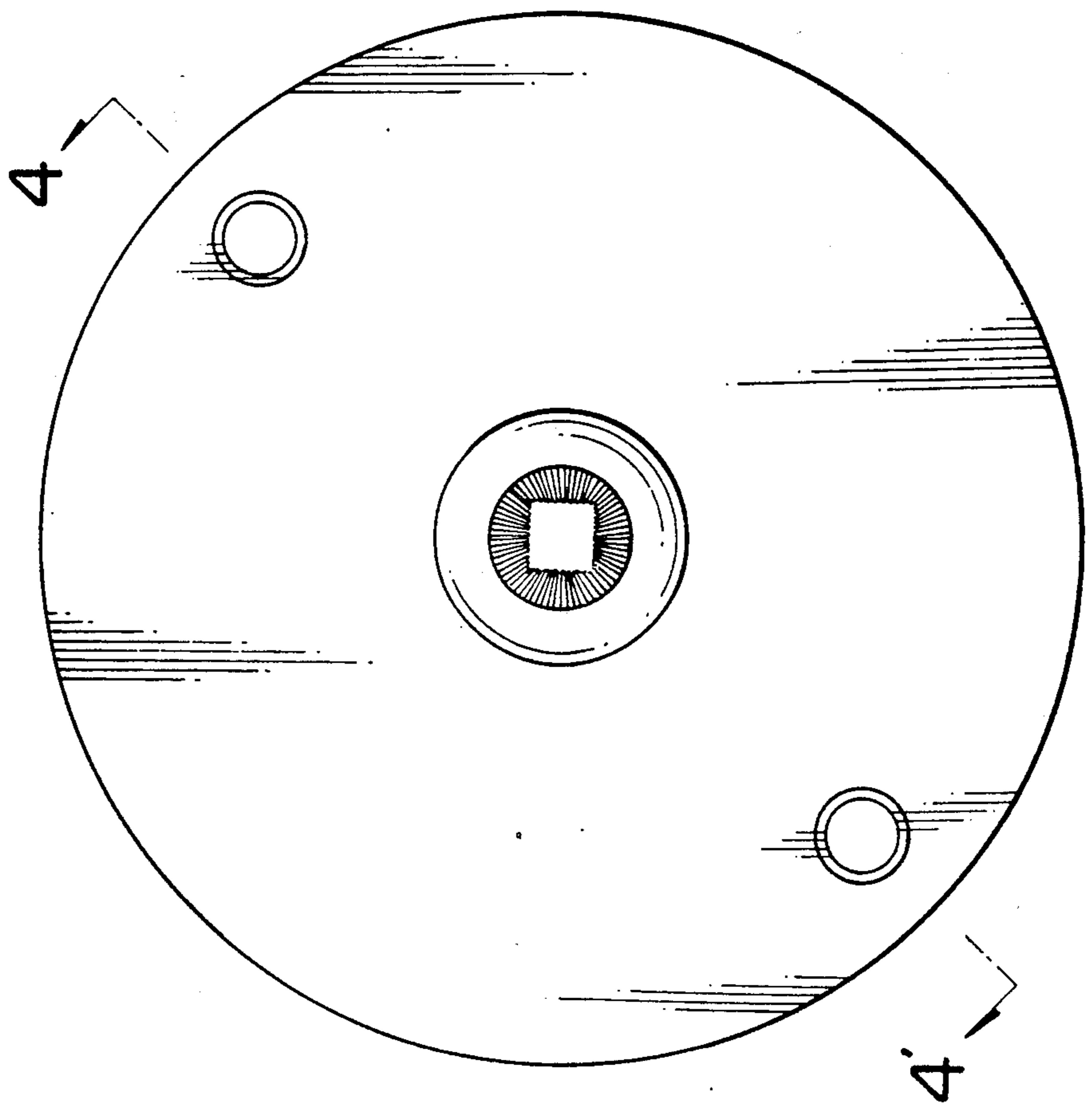


FIG. 3

